The 8th International Conference on Microelectronics and Plasma Technology I The 9th International Symposium on Functional Materials

Joint International Conference on ICMAP 2020 & ISFM 2020

August 16-20, 2020IAugust 16-19, 2020PHOENIX JEJU Hotel & Resort, Jeju Island, Korea

Dr. Julian Schulze

Department of Electrical Engineering, Ruhr-University Bochum, Germany

Department of Physics, West Virginia University, USA

School of Physics, Dalian University of Technology, Dalian, China



University Education

 Ruhr- University Bochum, Germany Habilitation, Plasma Technology, 2019 Ph.D., Physics, 2009 Diploma, Physics, 2006

Academic and Research Positions

- Ruhr University Bochum, Germany
 Akademischer Rat, Department of Electrical Engineering
- West Virginia University, USA
 Adjunct Associate Professor, Department of Physics
- Dalian University of Technology, China
 Visiting Research Professor, School of Physics

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Research Interests

- · Low Temperature Plasma Technology
- Radio Frequency Plasmas
- Control of Particle Dynamics and Distribution functions

Selected Academic Honors and Awards

- Hershkowitz award (2015, Plasma Sources Science and Technology)
- Award for Outstanding Quality of Teaching, Ruhr-University Bochum (5x5000 award, 2012)
- Hans Werner Osthoff award for Plasma Physics (Max-Planck society, 2012)
- Ph.D. award of the European Physical Society Plasma Physics Division (2011)

Publications

110 publications in low temperature plasma science in peer reviewed international journals (2796 citations, H-index: 31, Google Scholar: <u>https://scholar.google.de/citations?user=7CYrMRAAAAAJ&hl=de</u>)

250 contributions to national and international conferences on low temperature plasma science.

Other activities

- Editorial Board Member: Plasma Sources Science and Technology
- Guest-Editor Plasma Sources Science and Technology (special issues on electron heating in technological plasmas, plasma-surface interactions, and Voltage Waveform Tailoring)
- GEC Executive Committee Chair Elect